Joint International Conference on The 8th ICMAP & The 9th ISFM

January 17-20, 2021 | Online Conference

[WB2] Plasma Diagnostics and Process Monitoring Technology III	
Date / Time	January 20 (Wed.), 2021 / 11:00-12:20
Place	Channel B
Session Chair(s)	Duk Sun Han (KFE, Korea)

[WB2-1] Invited

Tomography-Based Optical Diagnostics for Real-Time Monitoring of Spatial Uniformity in Microelectronics Processing Plasmas

Wonho Choe *KAIST, Korea*

[WB2-2]

Improvement of Triple Probe Measurement on Non-Maxwellian Plasmas

Namjae Bae, Jaemin Song, Jihoon Park, Haneul Lee, and Gon-Ho Kim Seoul Nat'l Univ., Korea

[WB2-3] Invited

Predictive Control of the Plasma Processes after Discontinuities in the OLED Display Mass Production Line Referring to the PI-VM Model

Seolhye Park¹, Jaegu Seong¹, Yeongil Noh¹, Yoona Park¹, Yongsuk Jang¹, Taeyoung Cho¹, Jae Ho Yang¹, and Gon-Ho Kim²

¹Samsung Display Co., Ltd., Korea, ²Seoul Nat'l Univ., Korea

11:00-11:30

11:50-12:20

11:30-11:50